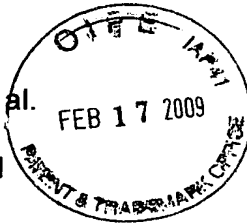


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

AF/IFW

In re the Application of:

Kazunari KURITA et al.



Art Unit: 1791

Application No.: 10/576,321

Examiner: Chaet, Marissa W.

Filed: 04/19/2006

Attorney Dkt. No.: 12054-0059

For: PROCESS FOR PRODUCING HIGH-RESISTANCE SILICON WAFERS AND
PROCESS FOR PRODUCING EPITAXIAL WAFERS AND SOI WAFERS (AS
AMENDED)

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.97(e), the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

As permitted by Rule 1.98(a), copies of the U.S. references are not included herewith.

Applicants respectfully submit that each item contained in the accompanying Information Disclosure Statement was first cited in a communication dated November 18, 2008 from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the Information Disclosure Statement, therefore, no fee is required.

Respectfully submitted,
CLARK & BRODY

A handwritten signature in cursive script, reading "Christopher W. Brody".

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Date: February 17, 2009